

## Initial Information Data Sheet

### Inventor Information

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### Application Information

Title Line One:: METHOD FOR CONTROLLING THE MORPHOLOGY  
Title Line Two:: OF DEPOSITED SILICON ON A SILICON DIOXIDE  
Title Line Three:: SUBSTRATE AND SEMICONDUCTOR DEVICES  
Title Line Four:: INCORPORATING SUCH DEPOSITED SILICON  
Total Drawing Sheets:: 4  
Formal Drawings?: Yes  
Application Type:: Utility  
Docket Number:: MIO 0037 VA

### Representative Information

Registration Number One:: 26,397  
Registration Number Two:: 27,262  
Registration Number Three:: 29,001  
Registration Number Four:: 39,564  
Registration Number Five:: 38,769  
Registration Number Six:: 33,758  
Registration Number Seven:: 42,695  
Registration Number Eight:: 44,494  
Registration Number Nine:: P-46,867  
Registration Number Ten:: P-46,506  
Registration Number Eleven:: 30,871  
Registration Number Twelve:: 34,095

**Continuity Information**

This application is a::

> Application One::

Filing Date::

Division of

09/072,262

May 4, 1998

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